



Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet

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of

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Complete if Known

Application Number	10/627,303
Filing Date	7/24/03
First Named Inventor	Patel
Art Unit	Not Yet Assigned
Examiner Name	Not Yet Assigned

Attorney Docket Number P109-US

U.S. PATENT DOCUMENTS

Examiner Initials ¹	Cite No. ¹	Document Number Number- Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
BUT		US- 3,511,727	05-12-1970	Hays, R.G.	
		US- 4,190,488	02-26-1980	Winters, H.F.	
		US- 4,310,380	12-12-1982	Flamm et al.	
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Examiner Initials ¹	Cite No. ¹	Foreign Patent Document Country Code ³ -Number ⁴ - Kind Code ⁵ (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
BUT		EP-0704884-A2	04-03-1996	Mehta, J.		
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BUT		WO-98/32163	07-23-1998	Tai et al.		

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Substitute for form 1449A/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Application Number	10/627.303
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Sheet	2	of	6	Attorney Docket Number	P109-US

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		Number - Kind Code ² (if known)			
BNJ		US- 6,409,876 B1	06-25-2002	McQuarrie, et al.	
		US- 6,396,619 B1	05-28-2002	Hubers, et al.	
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		US- 2003/0124848 A1	07/03/03	Chinn, et al.	
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		US-			

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BNJ		JP-1997/09251981-A	09-22-1997	Kazuaki et al.	
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BNJ		JP-1986/61181131-A	08-13-1986	Shinji et al.	

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Group Art Unit	Not Yet Assigned
Examiner Name	Not Yet Assigned

Attorney Docket Number P109-US

OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No. 1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T2
BNI		ALIEV et al., "Development of Si(100) Surface Roughness at the Initial Stage of Etching in F2 and XeF2 Gases Ellipsometric Study", Surface Science 442 (1999), pp. 206-214.	
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BNT		Kurt Williams, Etch Rates for Micromachining Processing-Part II, 2003 IEEE, Pgs 761-778, Journal of Microelectromechanical Systems, Vol. 12, No. 6, December 2003.	
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		"Xenon Difluoride Isotropic Etch System: Seeing is Believing", Surface Technology Systems Ltd. brochure, Newport, UK (date unknown).	
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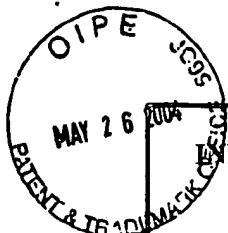
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